

(Use several sheets if necessary)

ATTY. DOCKET NO.:

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APPLICATION NO.:

10/691,403

APPLICANT:

Christophe MALEVILLE et al.

FILING DATE:

October 21, 2003

GROUP:

2812

• EXAMINER
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SUBCLASS

FILING DATE IF
APPROPRIATE

| | | | |
|----|--------------|---------|----------------|
| AA | 6,362,076 B1 | 03/2002 | Inazuki et al. |
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AB

AC

AD

AE

AF

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER

DATE _____

COUNTRY

CLASS

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TRANSLATION

YE

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| | | | |
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| AG | 2 797 713 | 02/2001 | France |
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AH

AI

NON-PATENT DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

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| AJ | Aditya Agarwal et al., "Efficient production of silicon-on-insulator films by co-implantation of He ⁺ with H ⁺ ," Applied Physics Letters, Vol. 72, pp. 1086-1088 (1998). |
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* **EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.